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WHAT IS CLAIMED IS:

- A conveyor device for a flexible substrate, said conveyor device comprising:

 a conveying means for continuously conveying a flexible substrate from
 one end to the other end;
- a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;

wherein center axes of the plurality of cylindrical rollers run parallel to each other; and

a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.

- 2. A device according to claim 1, wherein the radius R of the arc is in a range of 0.5 to 10 m.
- 3. A film formation apparatus for a flexible substrate, said film formation apparatus comprising:
- a conveying means for continuously conveying a flexible substrate from one end to the other end;

a plurality of cylindrical rollers being provided between the one end and the other end along an arc with a radius R;

wherein center axes of the plurality of cylindrical rollers run parallel to 20 each other; and

a mechanism for conveying the flexible substrate while the substrate is in contact with each of the plurality of cylindrical rollers.

- 4. An apparatus according to claim 3, wherein the radius R of the arc is in a range of 0.5 to 10 m.
- 5. An apparatus according to claim 3 further comprising:

a vacuum chamber;

an introducing means for introducing a gas into the vacuum chamber; a gas evacuation means; and

an energy supplying means for supplying an energy to make a plasma from the gas.

- 6. An apparatus according to claim 3,
- wherein the film formation apparatus is a plasma CVD apparatus.
 - 7. An apparatus according to claim 5, wherein the energy is an electromagnetic wave.